The 22nd Korean Conference on Semiconductors (KCS 2015)

제22회 한국반도체학술대회

2015년 2월 10일(화)-12일(목), 인천 송도컨벤시아

G. Device & Process Modeling, Simulation and Reliability 분과

Room C 1F / 106호

2015년 2월 12일(목) 13:10-14:40 [TC2-G] Device Physics and Characterization 2 좌장: 이성현 (한국외국어대학교), 박문수 (삼성디스플레이)

TC2 C 1	12.10 12.25	Extraction of Distance between Interfere Trans and Oxide Transform Bondon
TC2-G-1	13:10-13:25	Extraction of Distance between Interface Trap and Oxide Trap from Random
		Telegraph Noise in Gate-Induced Drain Leakage
		Youngsoo Seo, Sung-Won Yoo, Joonha Shin, Hyunsoo Kim, Hyunsuk Kim,
		Sangbin Jeon, and Hyungcheol Shin
		Inter-university Semiconductor Research Center (ISRC) and School of Electrical
		Engineering and Computer Science, Seoul National University
TC2-G-2	13:25-13:40	The Influence of Dummy Pattern on the RF Inductor Characteristics in 90nm
		CMOS Chip Layout
		Jong Keun Kim, Hee Kyeong Yang, Myoung Jun Jang, In Wook Cho, and Kyung
		Dong Yoo
		Technology Development in Image Development Group, Sk Hynix Inc.
TC2-G-3	13:40-13:55	Cost-Effective Approach using Deep N-type Well Junction in 180nm
		BCDMOS Technology
		Sekyung Oh, Daehoon Kim, Kwangsik Ko, Jaeho Hwang, Soonyeol Park, Jina
		Eum, Joowon Park, Kuemju Lee, Sanghyun Lee, Inwook Cho, and Kyungdong
		Yoo
		Technology Development team, SK Hynix Inc.
TC2-G-4	13:55-14:10	Origin of Kink Phenomenon in S ₁₁ -Parameter of Standard RF MOSFETs
		Ja-Hyun Ahn and Seonghearn Lee
		Department of Electronic Engineering, Hankuk University of Foreign Studies
TC2-G-5	14:10-14:25	A Characteristic Method of Extracting Intrinsic Threshold Voltage
		Fluctuation from Depletion Charge Variation
		Dongseok Cho, Jaekyu Lee, Junhee Lim, Jaerok Kahng, and Satoru Yamada
		Semiconductor R&D Center, Samsung Electronics
TC2-G-6	14:25-14:40	Design of Robust High-Voltage MOSFETs for Source Driver Applications
		Yon-Sup Pang, Eunkyung Park, Kwangho Park, Gukhwan Kim, Leeyeun Hwang,
		Boseok Oh, Sung-Bum Park, Jung Lee, and Taejong Lee
		MagnaChip Semiconductor, Corporate Engineering